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6.4 Light Intensity Through a Polarization Modulation Ellipsometer6.5 Waveform Analysis; 6.6 Calibration Procedures; 6.7 Errors; 6.8 Further Reading and References; Chapter 7. Multichannel Ellipsometry; 7.1 Introduction; 7.2 Overview of Instrumentation; 7.3 Rotating-Element Designs; 7.4 Concluding Remarks; 7.5 References; Part 3: Critical Reviews of Some Applications; Chapter 8. SiO2 Films; 8.1 Introduction; 8.2 Historical Perspective - Prior to 1970; 8.3 Modern Studies - Since 1970; 8.4 Conclusions; 8.5 References; Chapter 9. Theory and Application of Generalized Ellipsometry
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Sommario/riassunto

This second edition, edited by the world-renowned Dr. Rointain Bunshah, is an extensive update of the many improvements in deposition technologies, mechanisms, and applications. Considerably more material was added in Plasma Assisted Vapor Deposition processes, as well as Metallurgical Coating Applications.